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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 6956**

Jyun IWASHITA et al. : Docket No. 2004\_0468A

Serial No. 10/808,425 : Group Art Unit 1752

Filed March 25, 2004 : Examiner Sin J. Lee

NEGATIVE RESIST MATERIAL AND **Mail Stop: Amendment**  
METHOD FOR FORMING RESIST PATTERN

**RESPONSE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Official Action dated April 19, 2005, please amend the present application as follows: